

INDUCTIVELY COUPLED RF PLASMA REACTOR AND
PLASMA CHAMBER ENCLOSURE STRUCTURE THEREFOR
INVENTOR: COLLINS, et al. DKT: 306 D11

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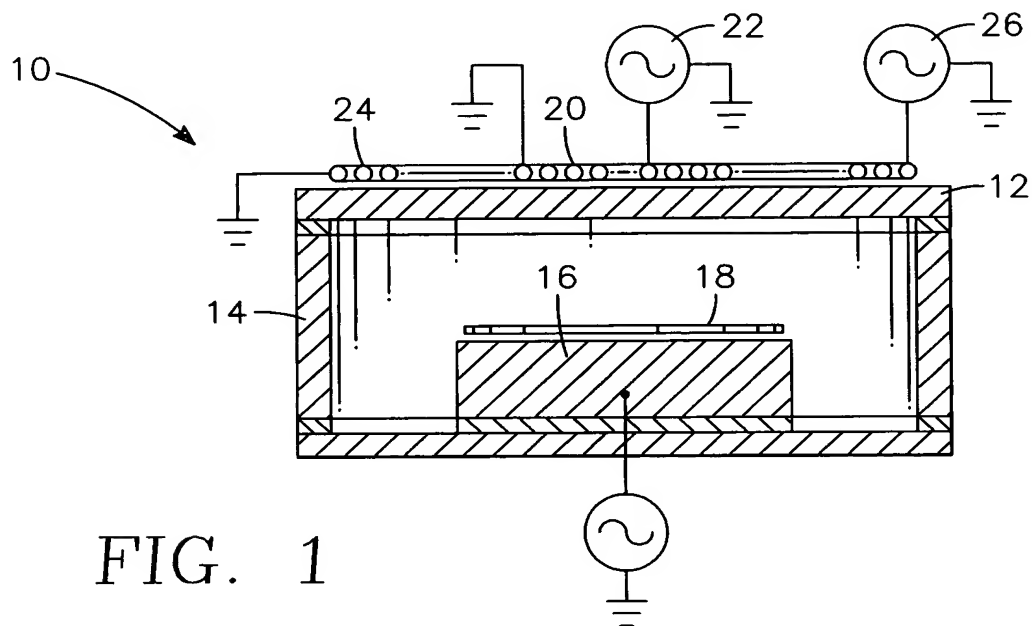


FIG. 1

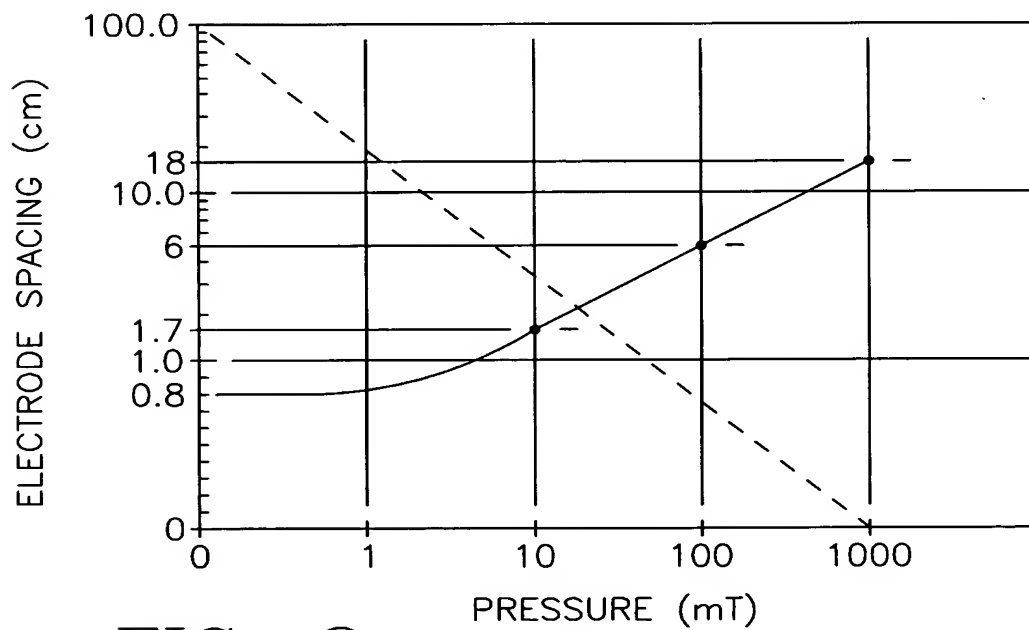


FIG. 2

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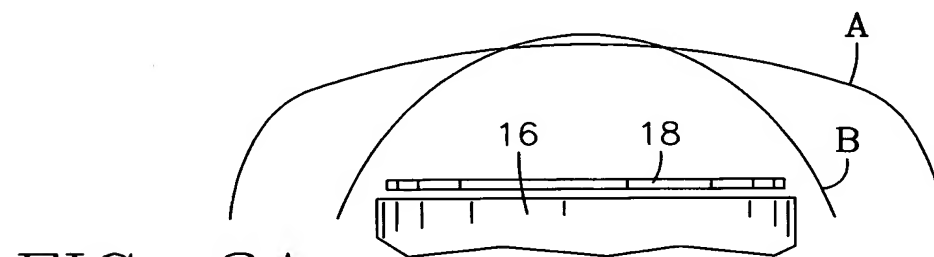


FIG. 3A

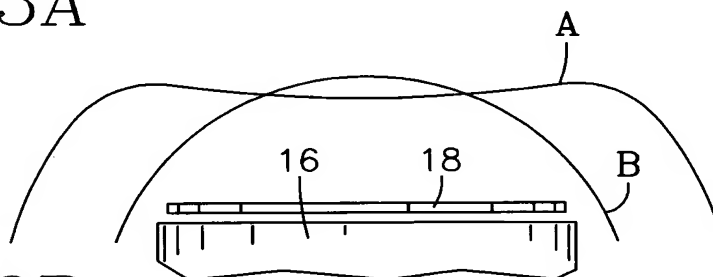


FIG. 3B

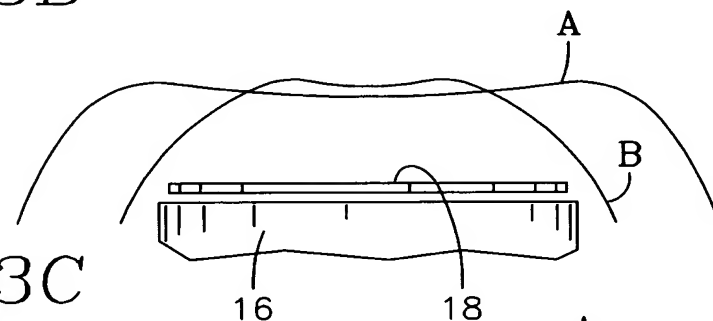


FIG. 3C

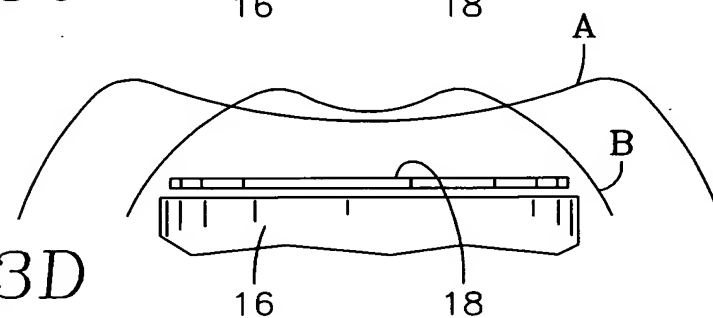


FIG. 3D

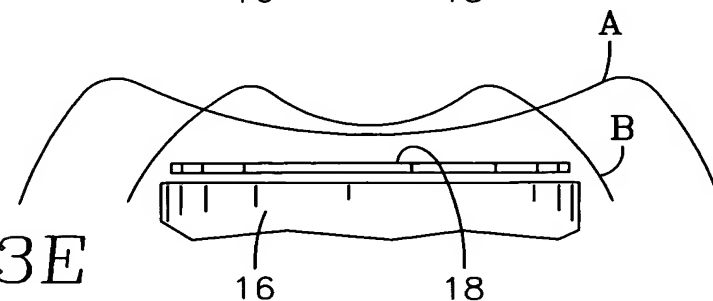


FIG. 3E

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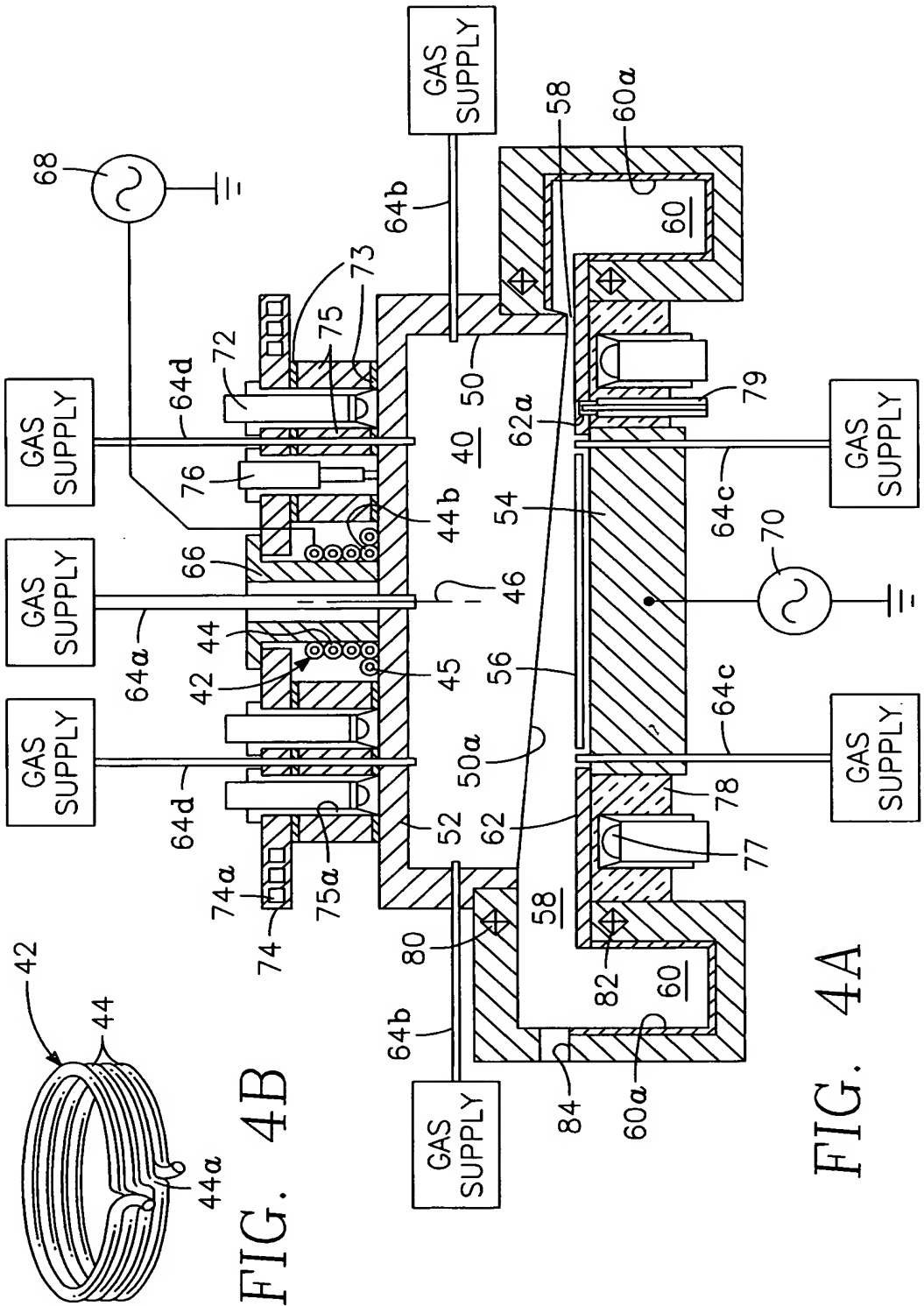


FIG. 4A

FIG. 4B

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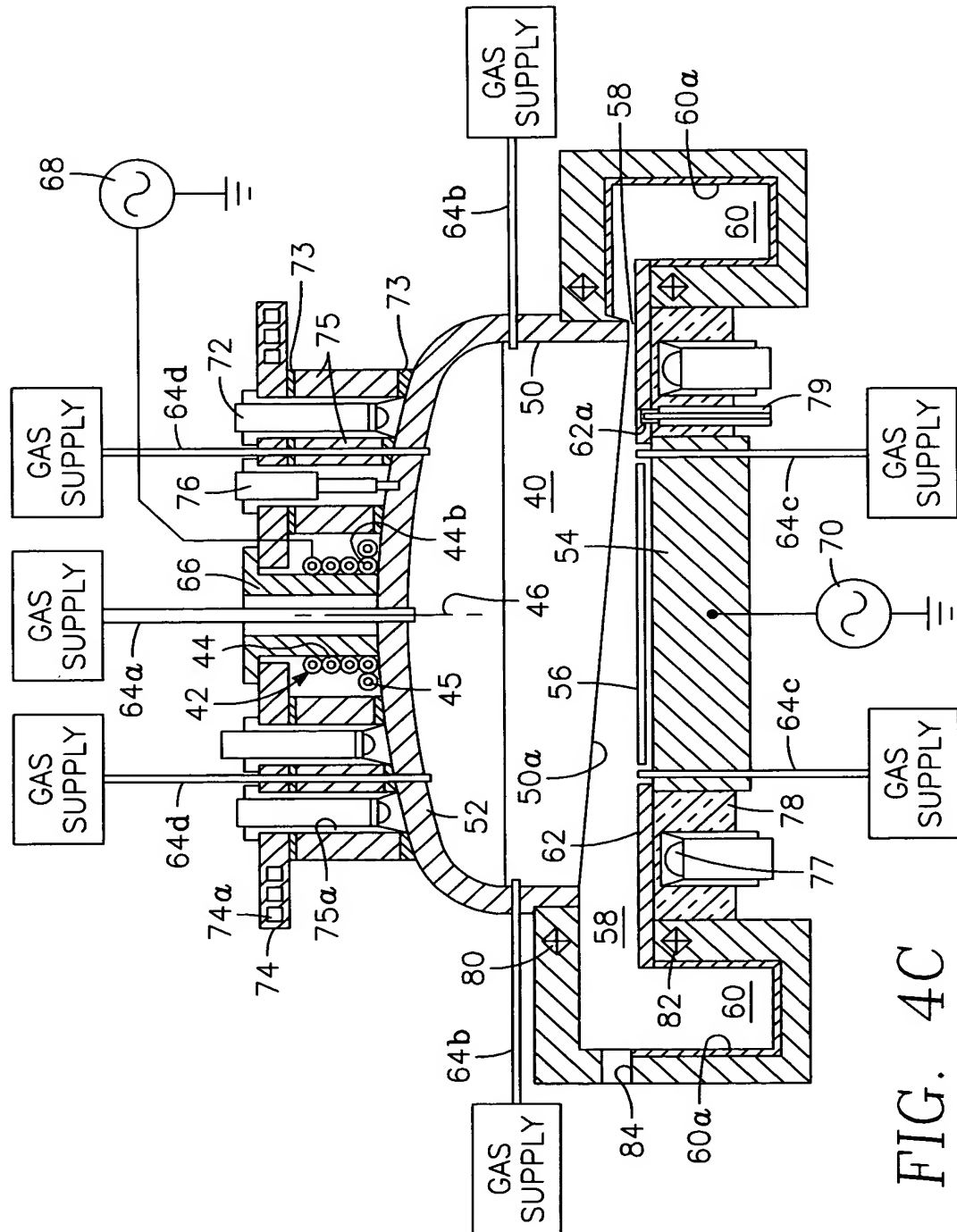
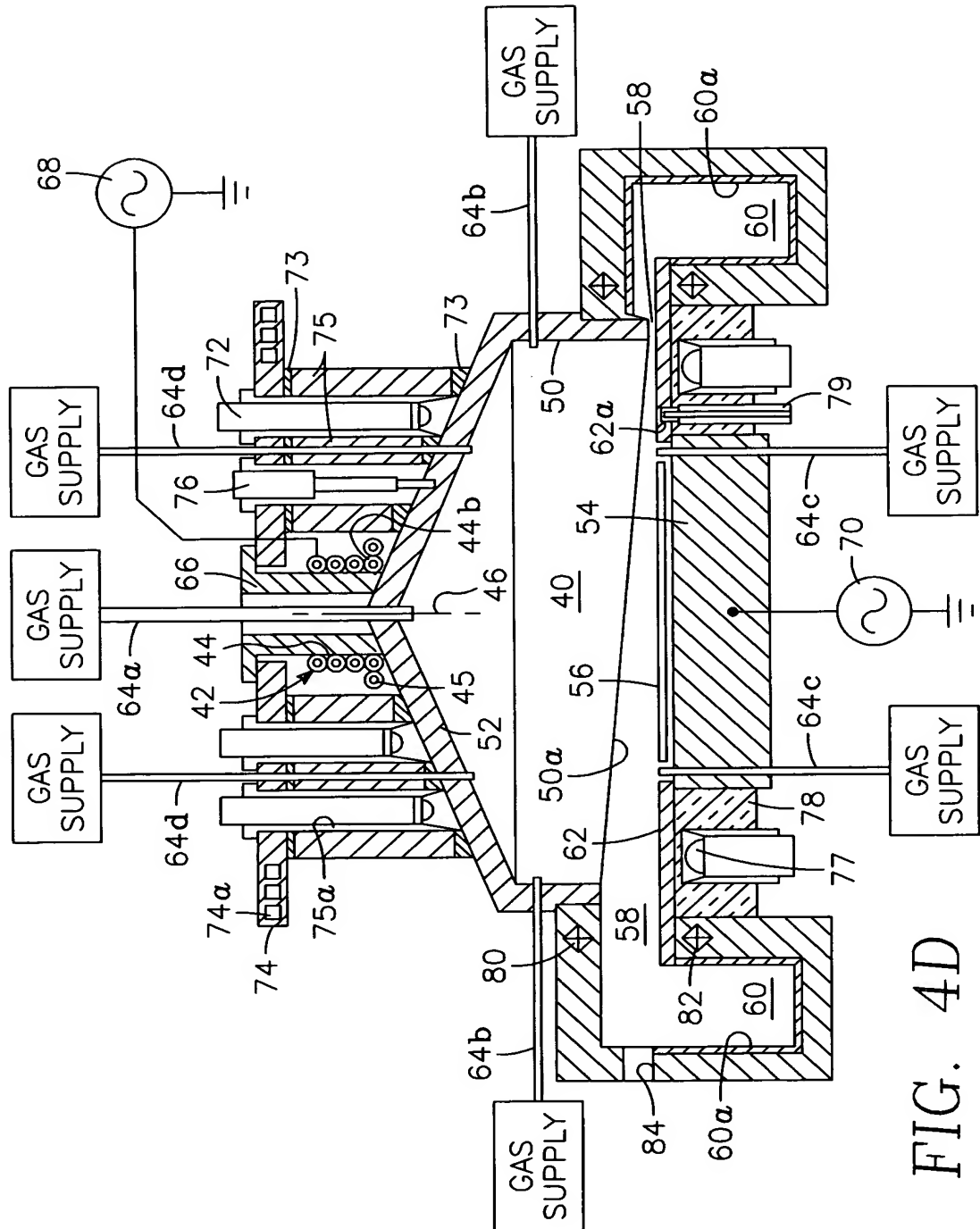
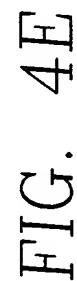


FIG. 4C

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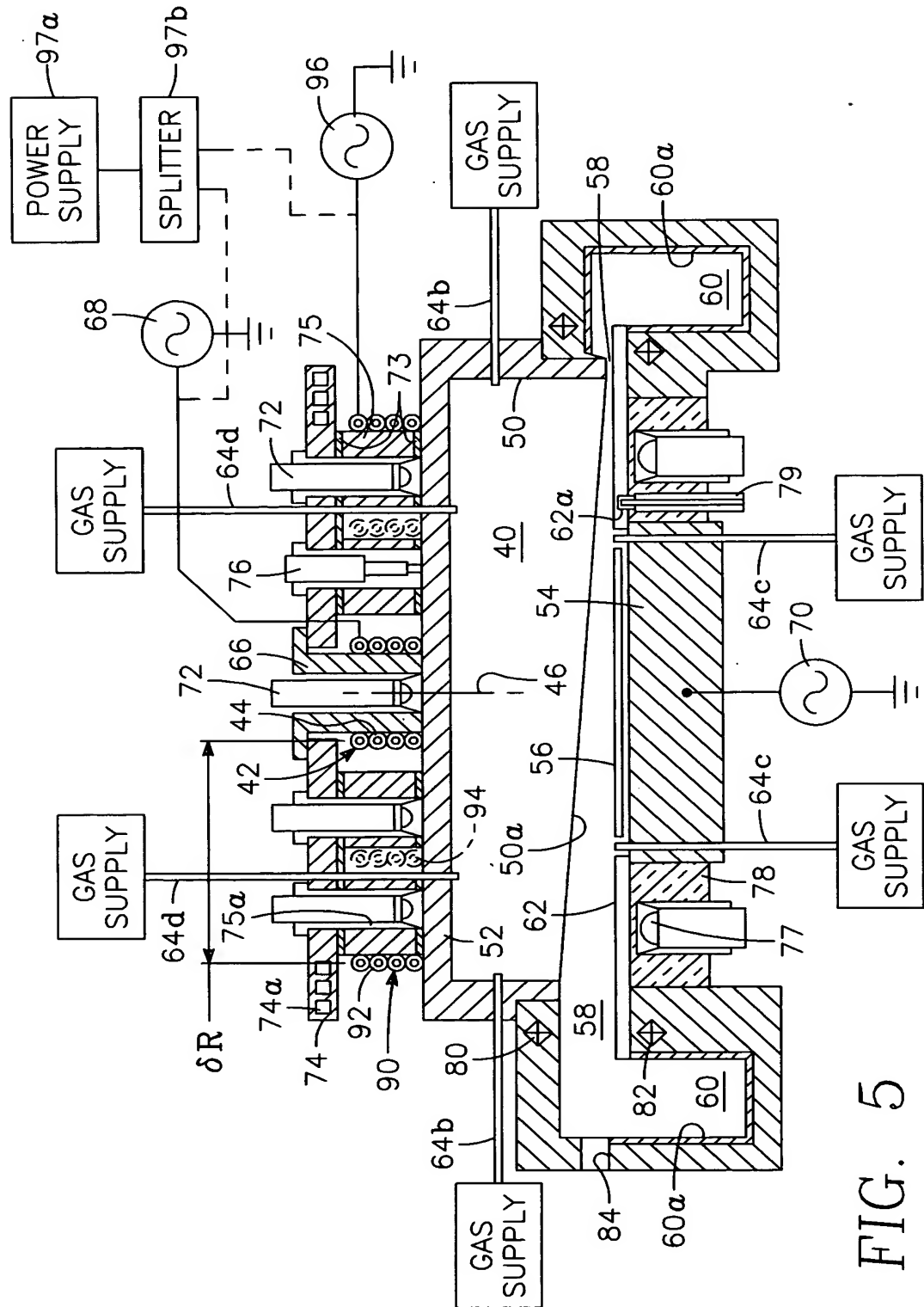


FIG. 5

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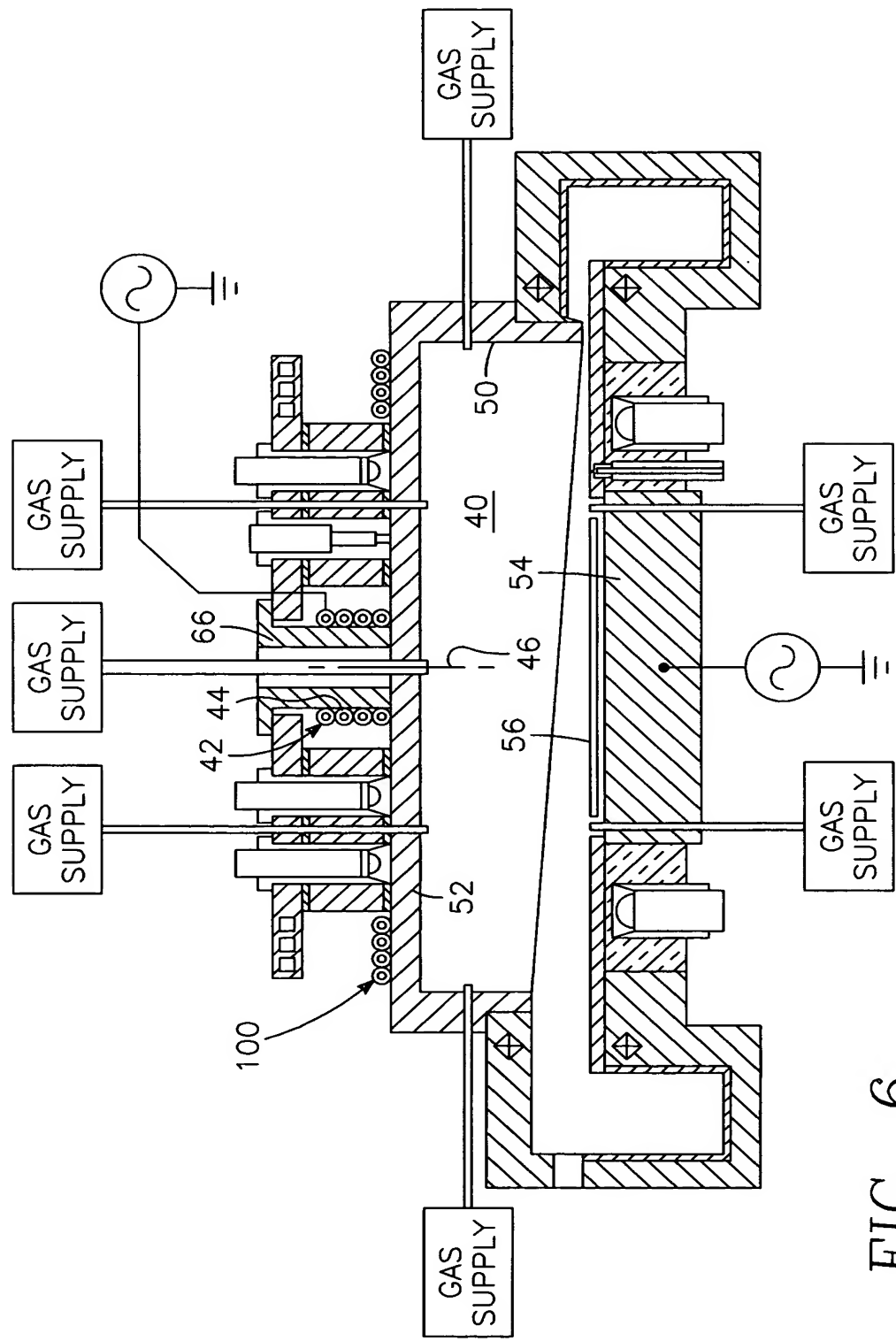
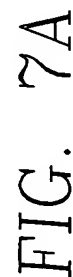
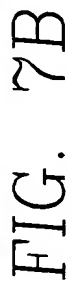
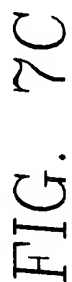


FIG. 6

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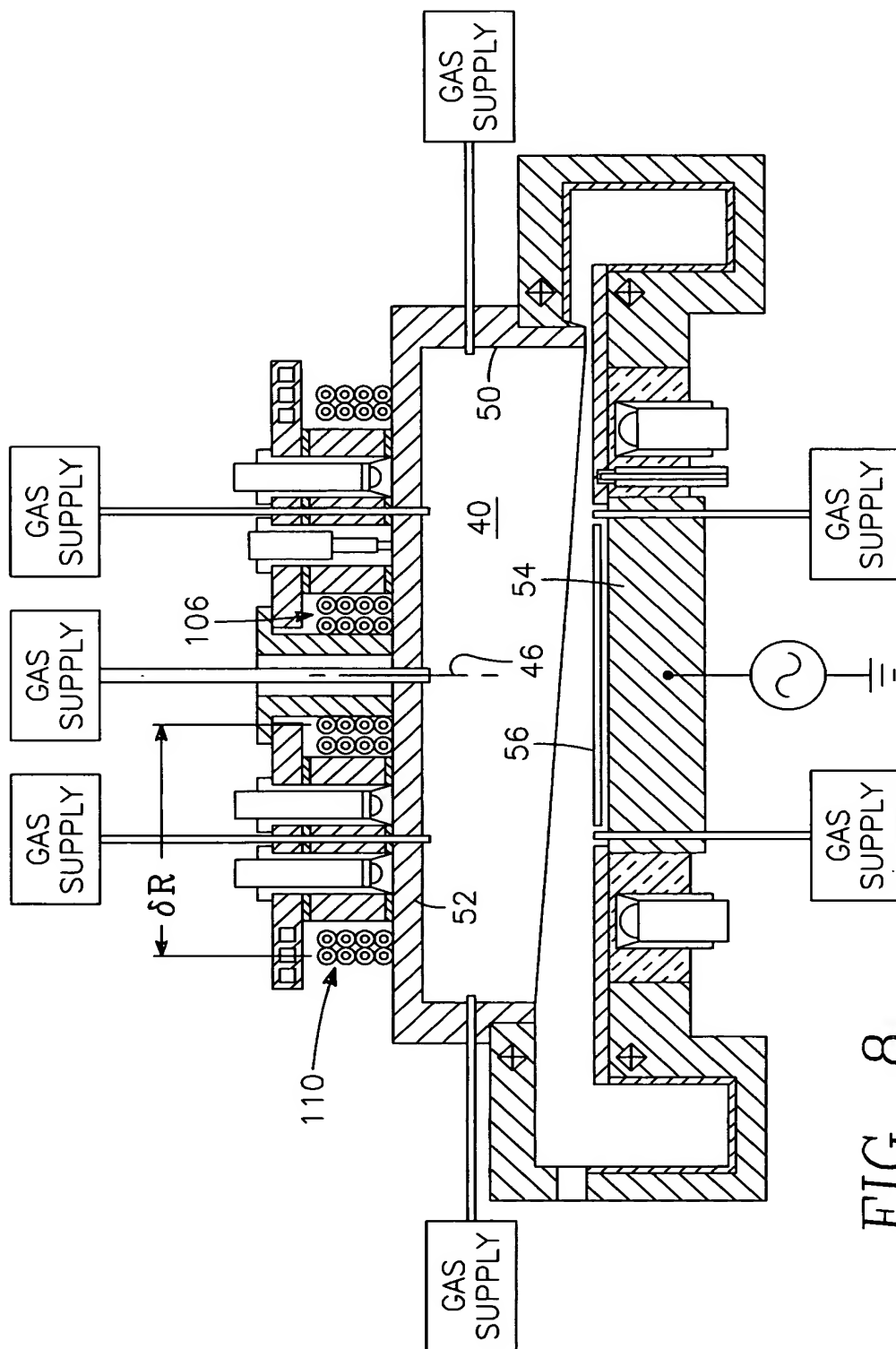
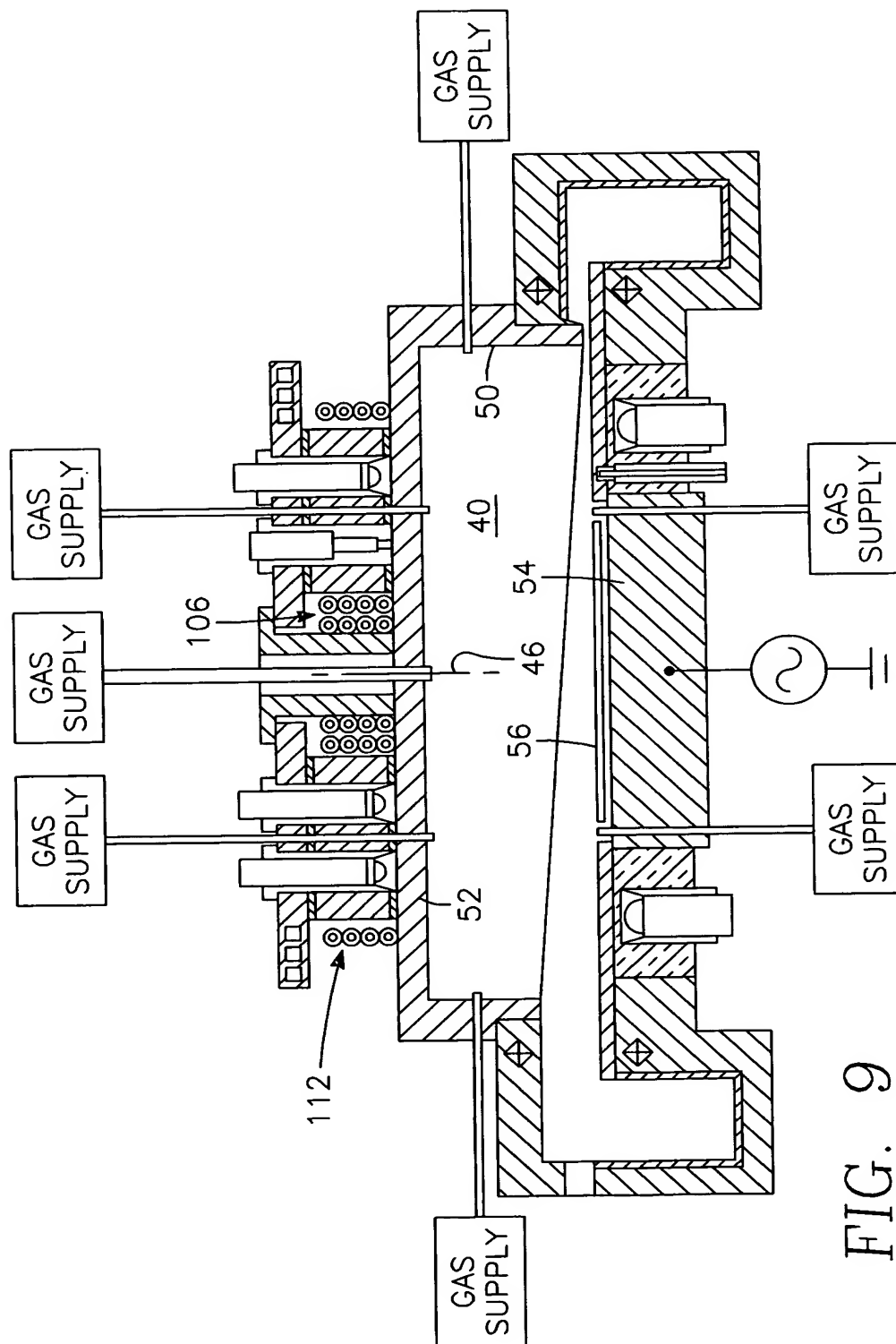


FIG. 8

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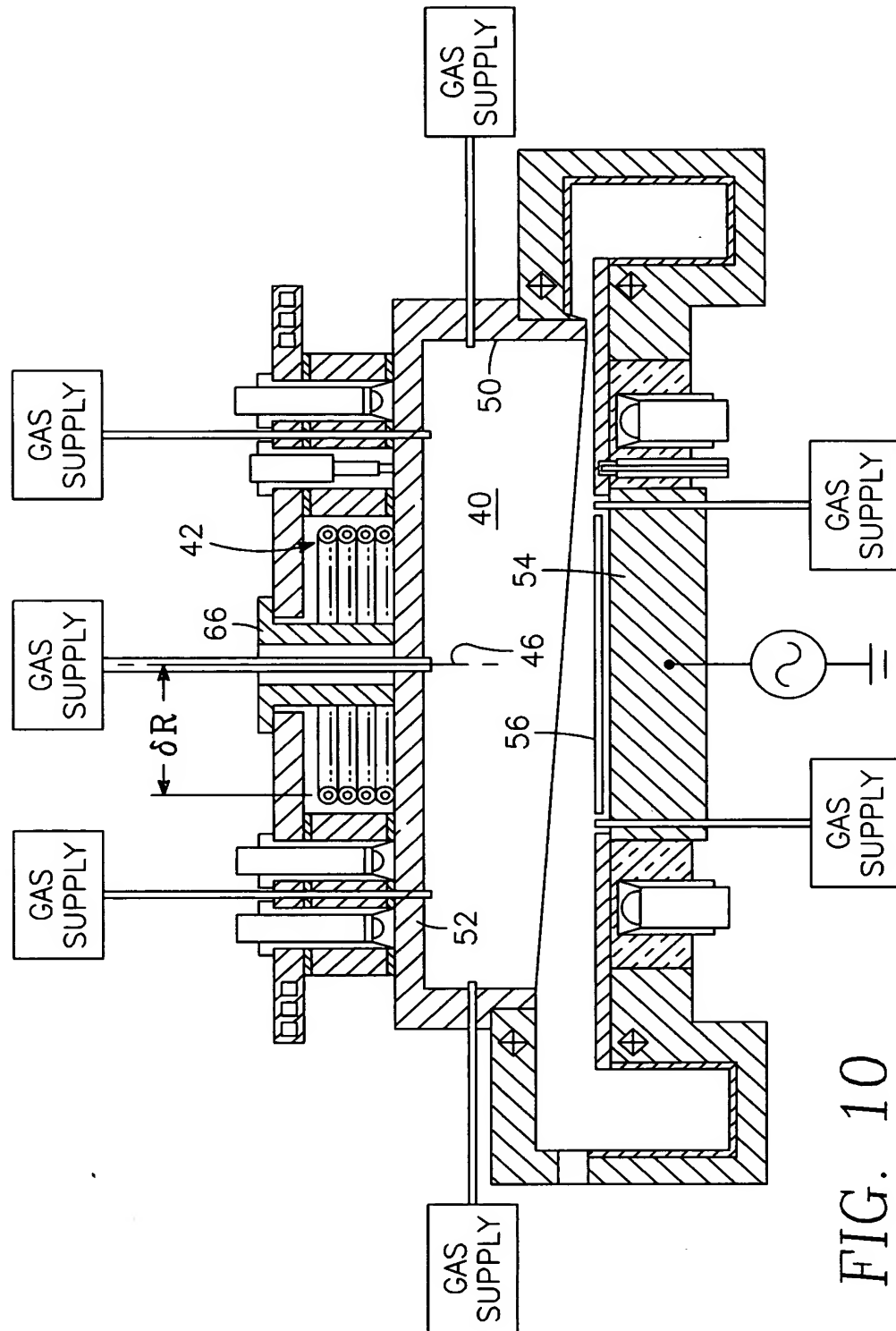


FIG. 10

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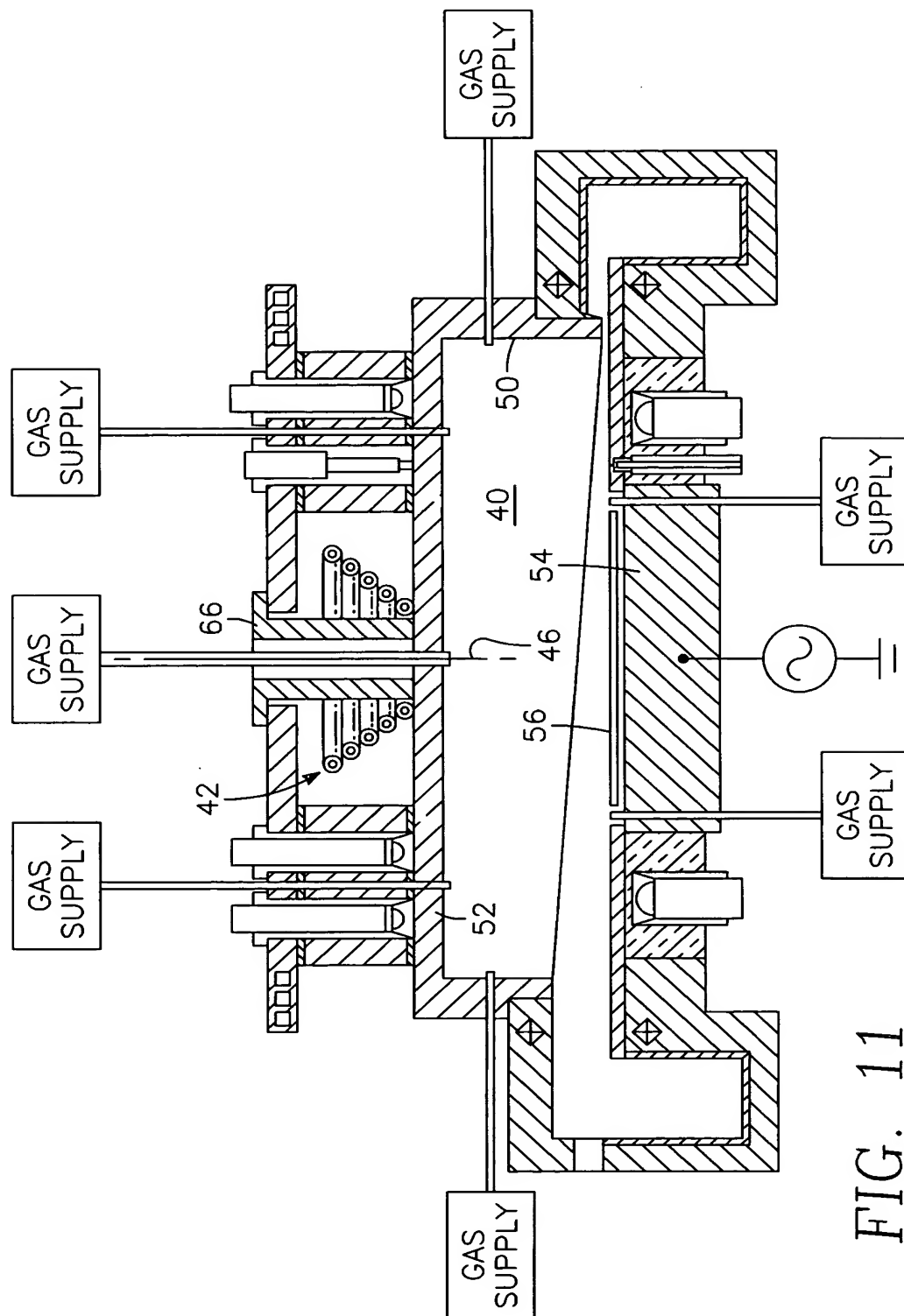
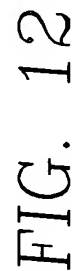


FIG. 11

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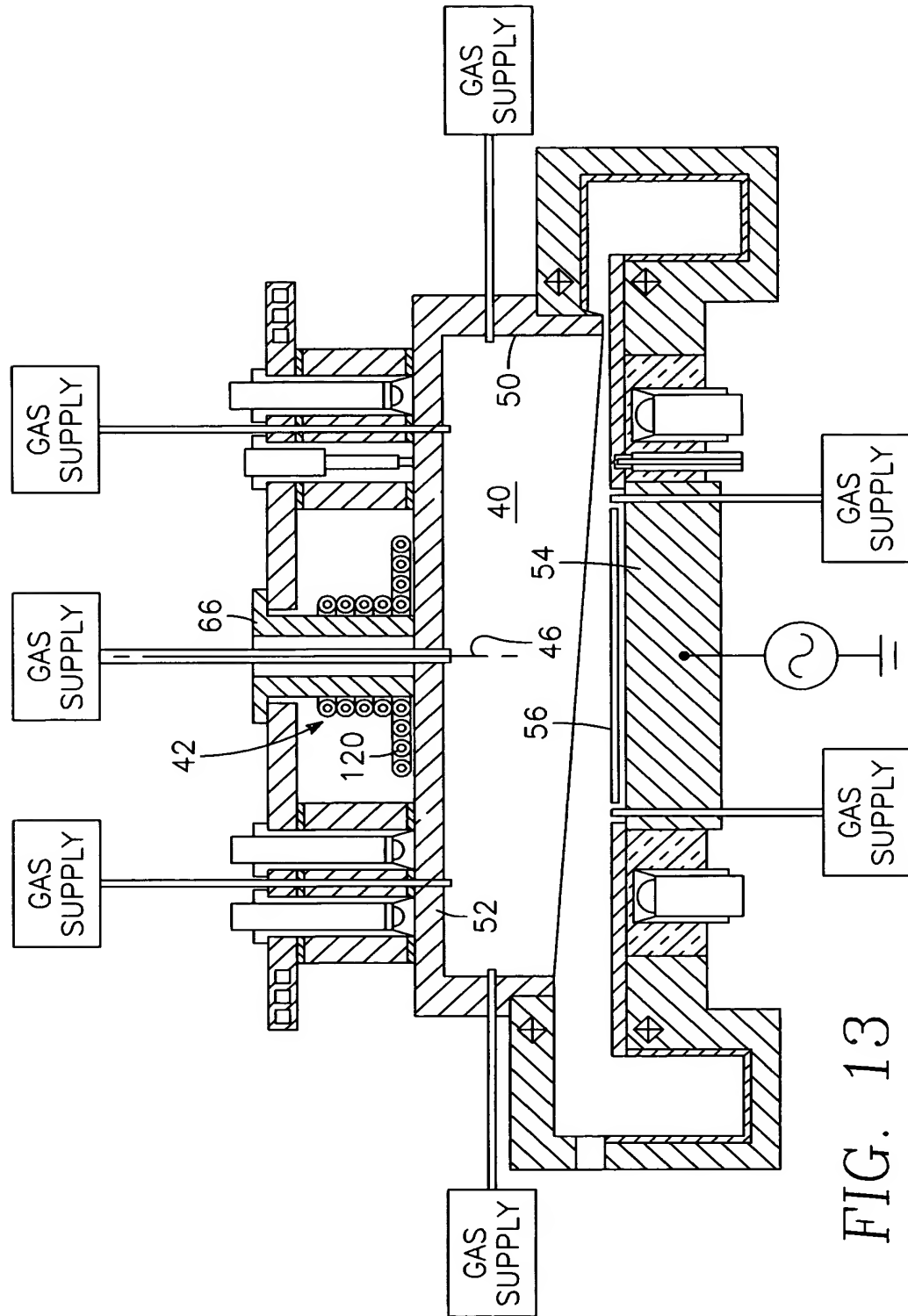
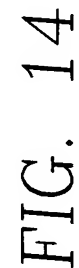
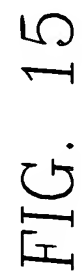


FIG. 13

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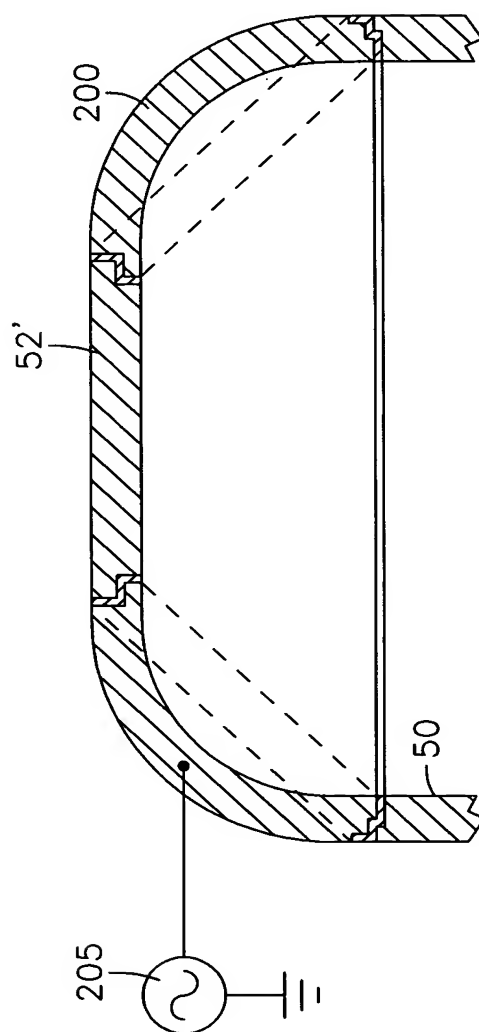


FIG. 16

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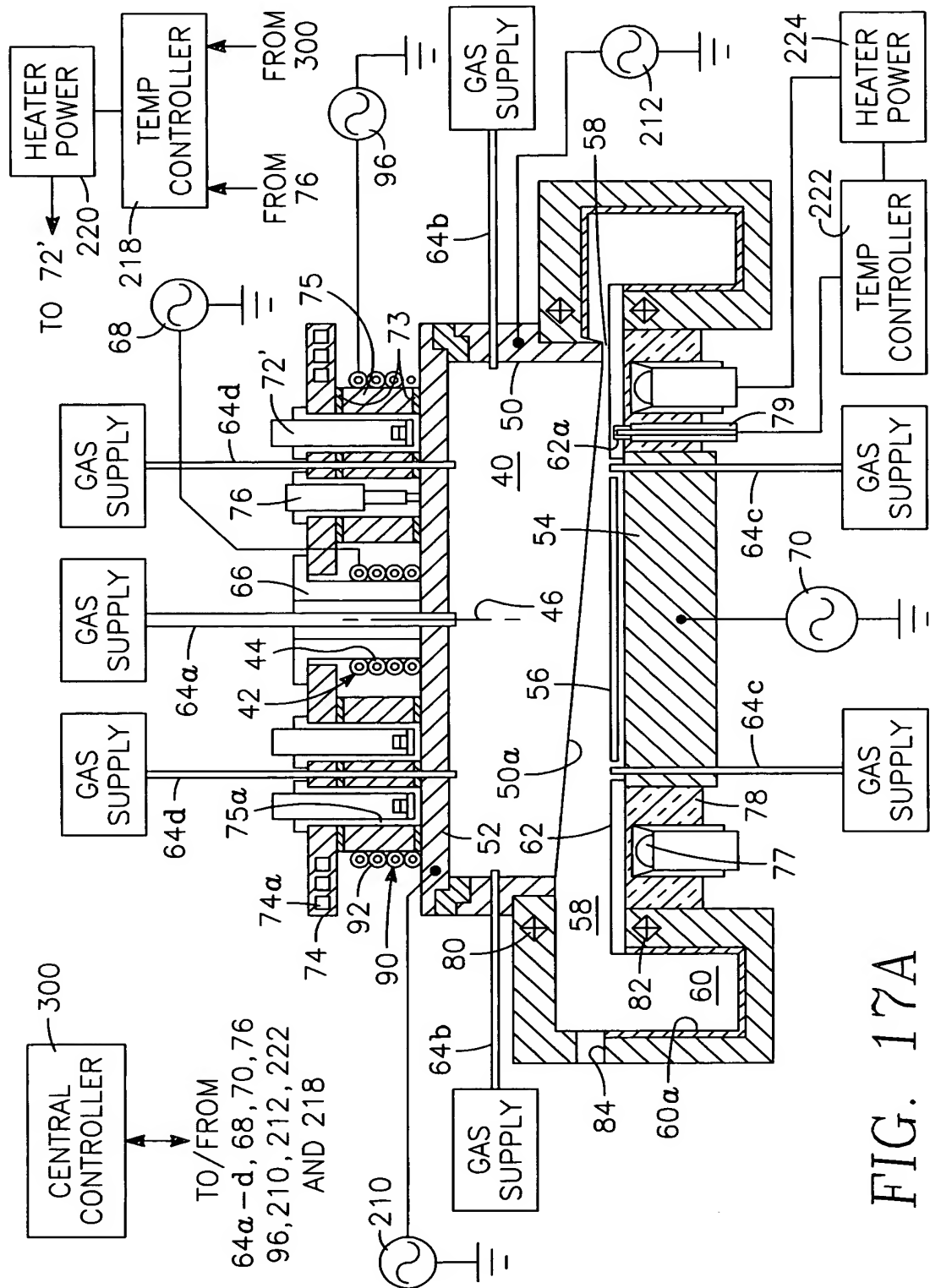


FIG. 17A

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